

Filament discharge enhances field emission properties by making twisted carbon nanofibres stand up

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Abstract

Twisted carbon nanofibres, named carbon nanotwists, in a flocculated form were pasted, printed on the conductive silicon substrate and then treated by dielectric barrier discharge using He and N₂ gases. Vertically upright nanofibres were clearly obtained by ‘filament discharge mode’ in N₂ gas. As the treating time increased up to ~60 s, the height of the nanofibre tips became uniform. Consequently, the field emission property was greatly enhanced and showed a threshold electric field of 4.6 V μm^{-1} and a maximum current of 0.433 mA cm^{-2} at 8 V μm^{-1} .

(Some figures in this article are in colour only in the electronic version)

1. Introduction

The recent development of the synthesis of micro- or nanometre-sized carbon tubular and coiled structures has drawn much attention to the application of these materials in electronics [1–3]. Depending on the catalyst and the process conditions, each of them can be formed from hydrocarbons in chemical vapour deposition (CVD) [4] and plasma-enhanced CVD [5–7]. We have focused on the formation of helical carbon nanofibre (HCNF) and its application to a field emitter device [8]. HCNF is categorized as either a spring-like helix form (carbon nanocoil (CNC)) [9–13] or a twisted form (carbon nanotwist (CNTw)) [14–16], depending on the internal diameter. These materials are applicable to field emission display owing to their high aspect ratio and electrical conductivity [12, 13, 16]. Some techniques for fabrication of

field emitter devices, including direct growth [17], screen-printing [18], spraying [19] and electrophoresis [20], are well known. Table 1 shows the drawbacks and advantages of each of these four techniques. Screen-printing and spraying are inexpensive and simple processes with the advantage of large-area treatment. However, HCNF must be made to stand up in the emitter to obtain effective field emission properties.

So far, stand-up treatments including adhesive tape [21], heat treatment [22] and excimer laser irradiation [23] have been reported. Making HCNF stand by adhesive tape application is a simple method, but problems of surface contamination and exfoliation of HCNF from the substrate arise. Laser irradiation is extremely expensive even if it is possible to treat a surface uniformly. In heat treatment, available substrates are limited due to high temperature (~400 °C). A new way to stand up HCNF and thus overcome the problems and drawbacks previously reported is awaited.

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